

Improvement of PS Measurement by Phase Compensation Method and Profile Fitting Method in White Light Phase Shifting Interferometry : Retraction

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The referenced paper [Curr. Opt. Photon. 2, 340-3018] has been retracted. © 2018 Optical Society of Korea
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The paper [1] has been retracted at the request of the authors and by the Code of Research Ethics of the OSK after the review of Research Ethics Committee.

The original article was published on 25 June 2018, and was retracted on 25 August 2019.

REFERENCES

1. D. H. Ku, S. M. Lee, H. N. Roh, T.-W. Kim, and H. J. Pahk, "Improvement of PS measurement by phase compensation method and profile fitting method in white light phase shifting interferometry," *Curr. Opt. Photon.* **2**, 340-347 (2018).